

ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

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Title of Invention

METHOD OF PLANARIZING SPIN-ON MATERIAL LAYER AND
MANUFACTURING PHOTORESIST LAYER

Application Number :

Confirmation Number:

First Named Applicant: Jefferson Lu

Attorney Docket Number: 12474-US-PA

Art Unit:

Examiner:

Search string: (6482716 or 6630397).pn

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	6482716	2002-11-19	Wohlfahrt et al.		438	427
	2	6630397	2003-10-07	Ding et al.		438	636

Signature

Examiner Name	Date